

3 predetermined pattern a second object is moved, thereby
4 exposing sequentially a plurality of defined regions on said
5 second object, comprising:

6 effecting an exposure onto one of the plurality of the
7 defined regions on said second object while moving said
8 second object in a predetermined direction, and

9 after finishing the exposure, moving said second object
10 in a direction intersecting with said predetermined
11 direction while moving said second object in said
12 predetermined direction.--

1 --173. A scanning exposure method in which in
2 synchronism with movement of a first object formed with a
3 predetermined pattern a second object is moved, thereby
4 exposing sequentially a plurality of defined regions on said
5 second object, comprising:

6 effecting an exposure onto one of the plurality of the
7 defined regions on said second object while moving said
8 second object in a predetermined direction, and

9 after finishing the exposure, accelerating said second
10 object in a direction intersecting with said predetermined
11 direction while decelerating said second object in said
12 predetermined direction.--

1 --174. A scanning exposure method in which in
2 synchronism with movement of a first object formed with a
3 predetermined pattern a second object is moved, thereby

4 exposing sequentially a plurality of defined regions on said
5 second object, comprising:

6 a first step of effecting an exposure onto one of the
7 plurality of defined regions on said second object while
8 moving said second object in a predetermined direction,

9 a second step of decelerating said second object in
10 said predetermined direction after finishing the exposure,

11 a third step of accelerating said second object in a
12 reverse direction to said predetermined direction after said
13 second step, and

14 a fourth step of accelerating and decelerating said
15 second object in a direction intersecting with said
16 predetermined direction during said second step and said
17 third step.--

1 --175. A scanning exposure method in which in
2 synchronism with movement of a first object formed with a
3 predetermined pattern a second object is moved, thereby
4 exposing sequentially a plurality of defined regions on said
5 second object, comprising:

6 effecting an exposure onto one of the plurality of
7 defined regions on said second object while moving said
8 second object in a predetermined direction, and

9 after finishing the exposure, moving said second object
10 in a direction inclined with respect to said predetermined
11 direction.--

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cont.

--176. A scanning exposure method in which in synchronism with movement of a first object formed with a predetermined pattern a second object is moved, thereby exposing sequentially a plurality of defined regions on said second object, comprising:

effecting an exposure onto one of the plurality of the defined regions on said second object while moving said first object in a first direction and moving said second object in a second direction corresponding to said first direction, and

after finishing the exposure, moving said second object in a direction inclined with respect to said second direction while decelerating said first object in said first direction.--

--177. A scanning exposure method in which in synchronism with movement of a first object formed with a predetermined pattern a second object is moved, thereby exposing sequentially a plurality of defined regions on said second object, comprising:

a first step of effecting an exposure onto one of the plurality of defined regions on said second object while moving said first object in a first direction and moving said second object in a second direction corresponding to said first direction, and

a second step of decelerating said second object in said second direction after finishing the first step,

13 a third step of accelerating said second object in a
14 reverse direction to said second direction after said second
15 step, and

16 a fourth step of decelerating said first object and
17 setting said first object to a reference position during
18 said second step and said third step.--

91 cont.
1 --178. A scanning exposure method in which in
2 synchronism with movement of a first object formed with a
3 predetermined pattern a second object is moved, thereby
4 exposing sequentially a plurality of defined regions on said
5 second object, comprising:

6 effecting an exposure onto one of the plurality of
7 defined regions on said second object while moving said
8 second object in a predetermined direction, and

9 after finishing the exposure, starting accelerating
10 said second object in a reverse direction to said
11 predetermined direction for preparing a scanning exposure
12 onto a next defined region while moving said second object
13 in a direction intersecting with said predetermined
14 direction.--

Sub 23
1 --179. A scanning type exposure apparatus in which in
2 synchronism with moving a first object in a predetermined
3 direction relative to an exposure beam, a second object is
4 moved, thereby exposing sequentially a plurality of defined
5 regions on said second object, comprising:

6 a movable body which holds said first object and is
7 movable in said predetermined direction; and

8 a first interferometer system which has a measurement
9 axis passing through a substantial center of an irradiation
10 region of said exposure beam and which measures positional
11 information of said movable body relating to a direction
12 intersecting with said predetermined direction.--

1 --180. An apparatus according to Claim 179, further
2 comprising:

3 a second interferometer system for measuring positional
4 information of said movable body relating to said
5 predetermined direction.--

1 --181. An apparatus according to Claim 180, wherein
2 said second interferometer system has a plurality of
3 measurement axes and measures rotational information of said
4 movable body also.--

1 --182. An apparatus according to Claim 179, wherein
2 said movable body is rotatable about a predetermined axis
3 passing through the irradiation region of said exposure
4 beam, while exposing said second object.--

1 --183. A scanning type exposure apparatus in which in
2 synchronism with moving a first object in a predetermined
3 direction relative to an exposure beam, a second object is

4 moved, thereby exposing sequentially a plurality of defined
5 regions on said second object, comprising:

6 a movable body which holds said first object;

7 a first interferometer system which has a plurality of
8 measurement axes for detecting positional information of
9 said movable body relating to said predetermined direction;

10 and

11 a reflection surface disposed separately on said
12 movable body in correspondence with said plurality of the
13 measurement axes.--

1 --184. An apparatus according to Claim 183, further
2 comprising:

3 a second interferometer system having a measurement
4 axis for detecting positional information of said movable
5 body with respect to a direction intersecting with said
6 predetermined direction; and

7 a reflection surface disposed on said movable body for
8 said second interferometer system and extended substantially
9 in parallel with said predetermined direction.--

1 --185. An apparatus according to Claim 184, wherein
2 the measurement axis of said second interferometer system
3 passes through a substantial center of the irradiation
4 region of said exposure beam --

1 --186. An apparatus according to Claim 184, wherein
2 said movable body is rotatable about a predetermined axis
3 passing through the irradiation region of said exposure
4 beam.--

1 --187. A scanning type exposure apparatus in which in
2 synchronism with moving a first object in a first direction,
3 a second object is moved in a second direction, thereby
4 exposing sequentially a plurality of defined regions on said
5 second object, comprising:

6 a first movable stage holding said first object;

7 a second movable stage holding said second object;

8 a first interferometer system outputting positional
9 information of said first stage;

10 a second interferometer system outputting positional
11 information of said second stage;

12 a first drive mechanism for moving said first stage in
13 said first direction;

14 a second drive mechanism for moving said second stage
15 in said second direction;

16 a projection optical system for projecting an image of
17 a pattern on said first object onto said second object; and

18 a controller which converts positional information in
19 said second direction of said second stage outputted from
20 said second interferometer system to speed information and
21 speed controls said second drive mechanism so that said
22 speed information may correspond to a constant speed V, and